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	Filing Date		2006-04-19	
	First Named Inventor	Karg et al.		
	Art Unit			
	Examiner Name			
	Attorney Docket Number	CH920030009US1		

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1	Nanostructuring with laser radiation in the nearfield of a tip from a scanning force microscope, YAU ET AL, Applied Physic Letters, Vol. 164, no. 1 29032, 1996-12-31	<input type="checkbox"/>
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